

Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 8/21/09 has been entered.

Allowable Subject Matter

2. Claims 1-13 are allowed.
3. The following is an examiner's statement of reasons for allowance: The closest prior art Yuda et al (2004/0083967) fails to teach or renders obvious to an apparatus including a flat-plate structure provided between the high frequency wave supply and the mounting unit, wherein the flat-plate structure is formed with a source gas supply port for supplying a source gas for film formation in to the mounting unit region and opening for allowing plasma generated in the high frequency wave supply unit side to pass to into the region on the mounting unit side and a plasma excitation gas supply port is at the lower side of the region on the high frequency wave supply unit side towards a central portion of the region as context of claim 1.
4. The prior art also fails to teach or renders obvious to a process for film forming utilizing a plasma film forming apparatus including a plasma generation region is formed between the mounting unit and the high frequency wave supply unit including the step of supplying the plasma excitation gas from a lateral side and a lower side of

the plasma generation region to a central portion of the plasma generation region and adjusting each of supply flow rates of the plasma excitation gases from the lateral side and the lower side of the plasma generation region as the context of claim 11.

5. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."
6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Shamim Ahmed whose telephone number is (571) 272-1457. The examiner can normally be reached on Mon-Thurs day (7:00-3:30) Every Friday Off.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine G. Norton can be reached on (571) 272-1465. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Shamim Ahmed
Primary Examiner
Art Unit 1792

SA
October 23, 2009

/Shamim Ahmed/
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